

Inventor: Eugene P. Marsh

Title: Platinum-containing Integrated Circuits and Capacitor
Constructions

Assignee: Micron Technology, Inc.

INFORMATION DISCLOSURE STATEMENT

PURSUANT TO 37 C.F.R. §§1.56, 1.97 AND 1.98

In compliance with 37 C.F.R. §§1.56, 1.97 and 1.98, your attention is directed to the United States patents and other references listed on the attached Form PTO-1449.

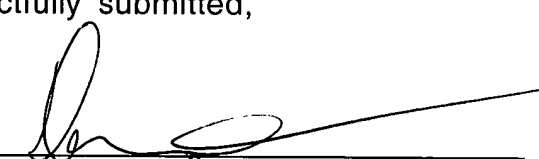
The listed references were cited by, or submitted to, the Office in the parent, co-pending application of the above-identified application. The above-identified application is a continuation of co-pending application Serial No. 09/421,625 filed October 19, 1999. Such prior disclosure is sufficient for the above-identified application as far as copies of the references are concerned. 37 C.F.R. §1.98(d) and MPEP §609(2). No admission is made regarding whether all the submitted references are prior art.

Citation of these references is respectfully requested.

Respectfully submitted,

Dated: 8/13/03

Attorney:


David G. Latwesen, Ph.D.
Reg. #38,533
WELLS ST. JOHN P.S.

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| Form PTO-1449 | | U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE | | ATTY. DOCKET NO. MI22-2382 | | PRIORITY SERIAL NO. Filed Herewith | |
| LIST OF ART CITED BY APPLICANT (Use several sheets if necessary) | | | | APPLICANT Micron Technology, Inc. | | | |
| | | | | PRIORITY FILING DATE 10/19/99 | | PRIORITY GROUP Unknown | |
| U.S. PATENT DOCUMENTS | | | | | | | |
| *Examiner Initial | | Document Number | Date | Name | Class | Subclass | Filing Date If Appropriate |
| | AA | 4,341,662 | 7/82 | Pfefferle | | | |
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| FOREIGN PATENT DOCUMENTS | | | | | | | |
| | | Document Number | Date | Country | Class | Subclass | Translation |
| | | | | | | | Yes No |
| | AI | 9-082666 | | Japan | | | |
| | AJ | 0 415 751 A1 | | EPO | | | |
| OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.) | | | | | | | |
| | AK | | Ju-Hong Kwan et al.; "Characterization of Pt Thin Films Deposited by Metallorganic Chemical Vapor Deposition for Ferroelectric Bottom Electrodes"; J. Electrochem. Soc., Vol. 144, No. 8, August 1997; pp. 2848-2854 | | | | |
| | AL | | M. Ino et al.; "Rugged surface polycrystalline silicon film deposition and its application in a stacked dynamic random access memory capacitor electrode"; J. Vac. Sci. Technol. B 14(2), March/April 1996; pp. 751-756 | | | | |
| | AM | | | | | | |
| | AN | | | | | | |
| | AO | | | | | | |
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| <small>*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.</small> | | | | | | | |

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| U.S. PATENT DOCUMENTS | | | | | | | |
| *Examiner Initial | Document Number | Date | Name | Class | Subclass | Filing Date If Appropriate | |
| | AA | 5,320,978 | 6/94 | Hsu | | | |
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| | Document Number | Date | Country | Class | Subclass | Translation | |
| | | | | | | Yes | No |
| | AK | JP 9051079 | 2/18/97 | Japan | | | |
| | AL | JP 8017939 | 6/3/03 | Japan | | | |
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| | AO | | | | | | |
| | AP | | | | | | |
| OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.) | | | | | | | |
| | AQ | | | | | | |
| | AR | | | | | | |
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